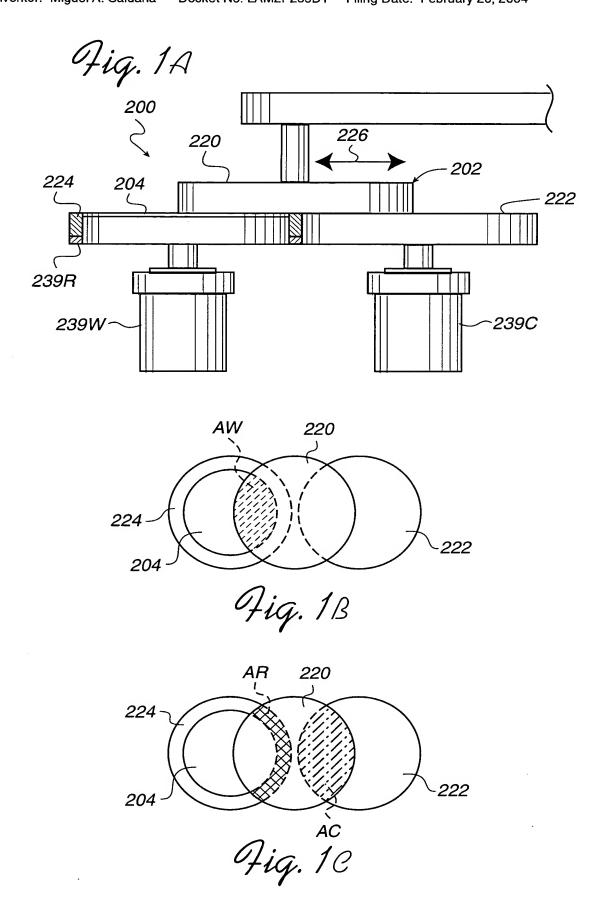
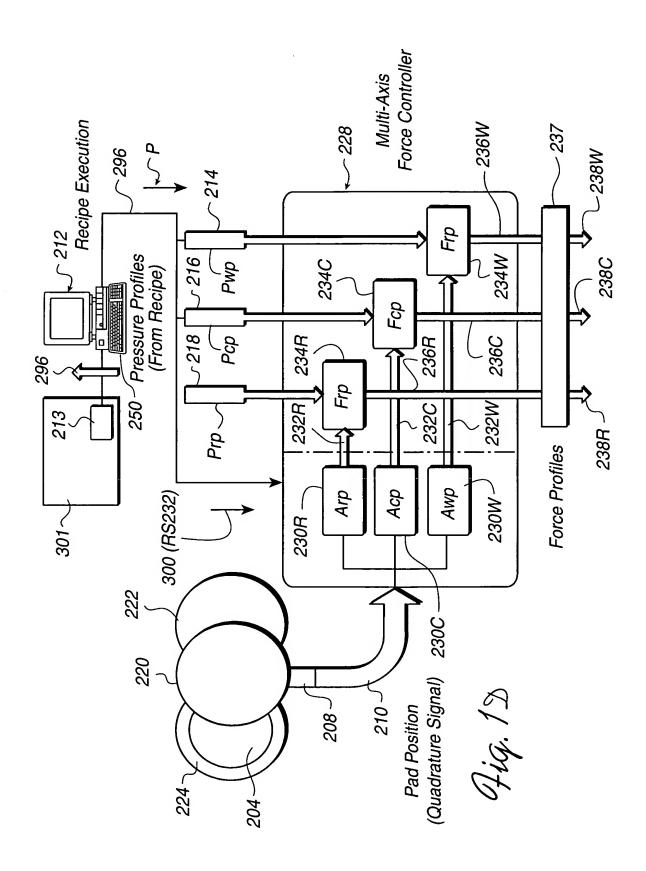
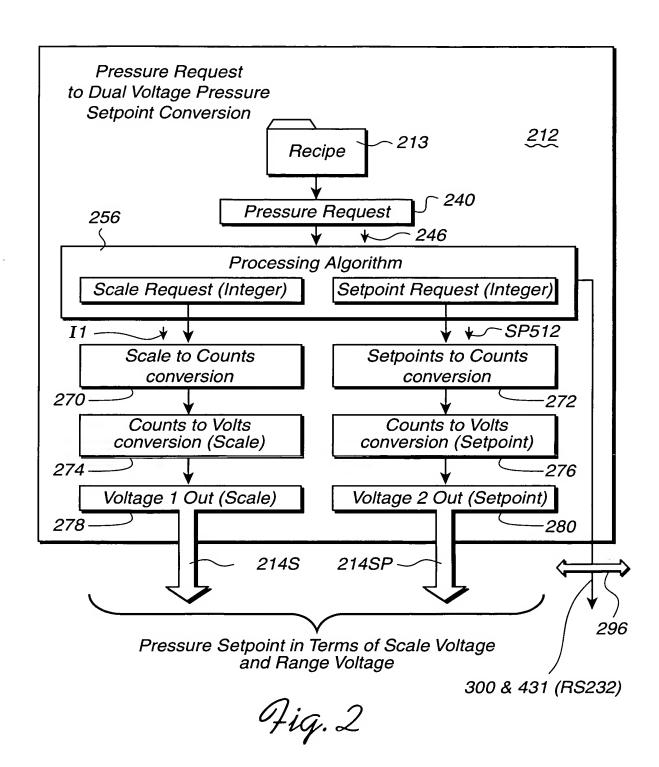
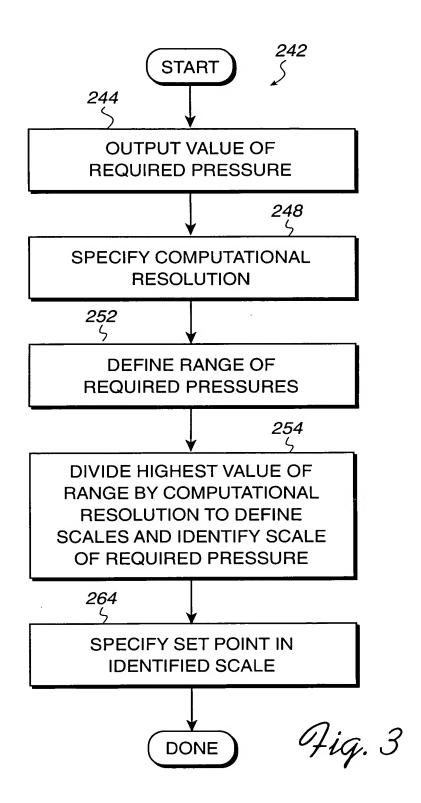
Title: METHODS WITH RESOLUTION ENHANCEMENT FEATURE FOR IMPROVING ACCURACY OF CONVERSION OF REQUIRED CHEMICAL MECHANICAL POLISHING PRESSURE TO FORCE TO BE APPLIED BY POLISHING HEAD TO WAFER Inventor: Miguel A. Saldana Docket No. LAM2P255D1 Filing Date: February 26, 2004









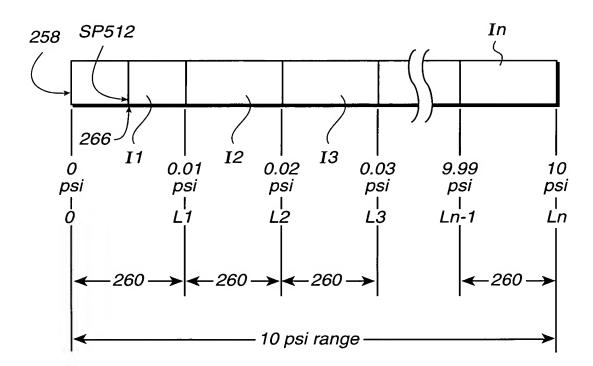
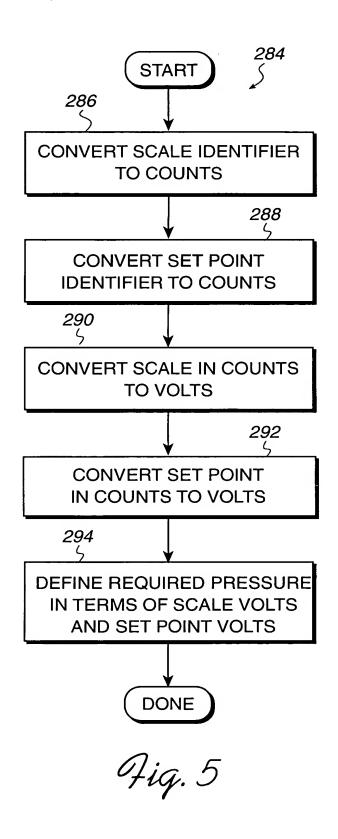
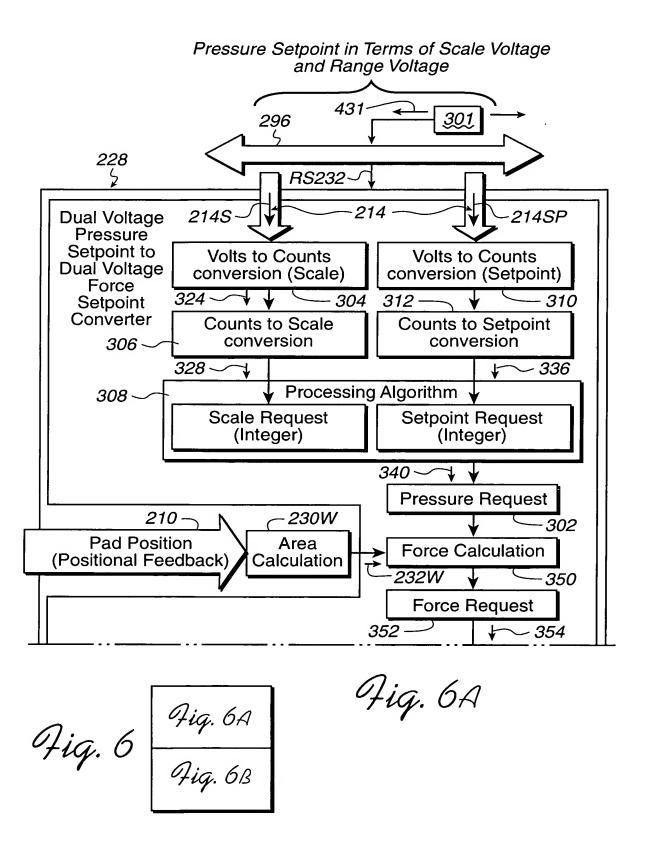
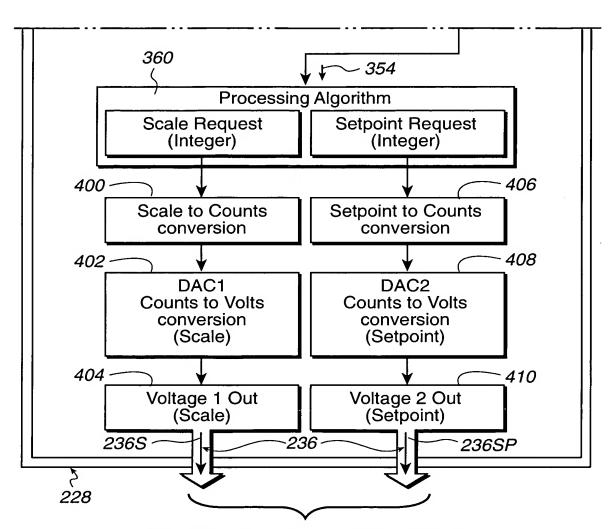


Fig. 4



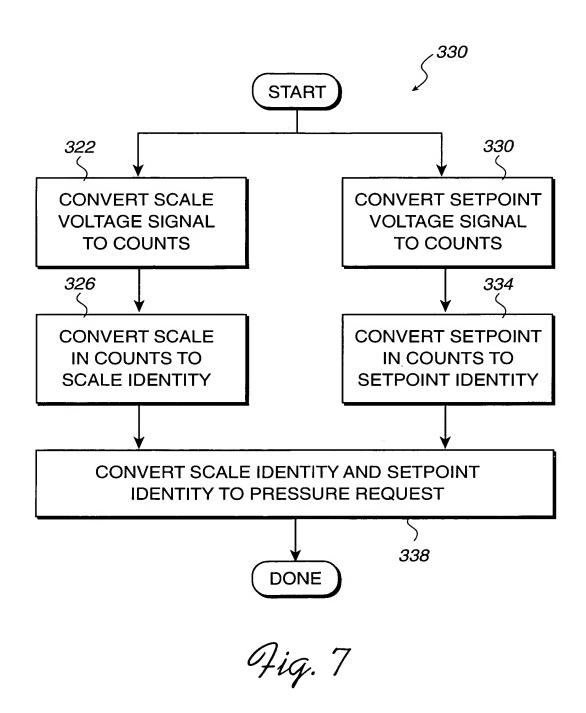


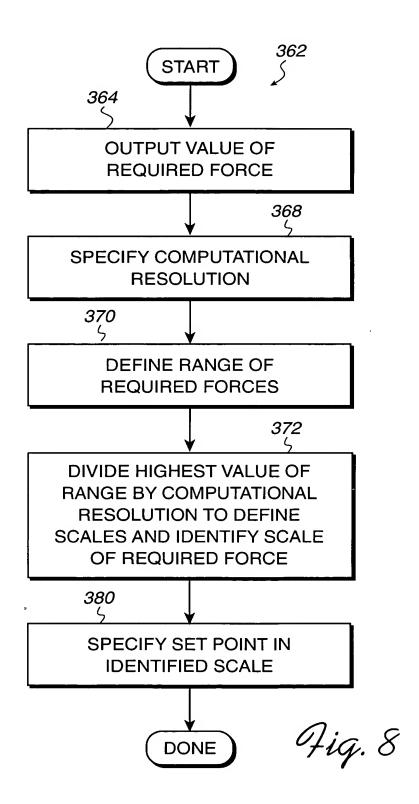
Inventor: Miguel A. Saldana Docket No. LAM2P255D1 Filing Date: February 26, 2004



Force Setpoint in Terms of Scale Voltage and Setpoint Voltage

Fig. 6B





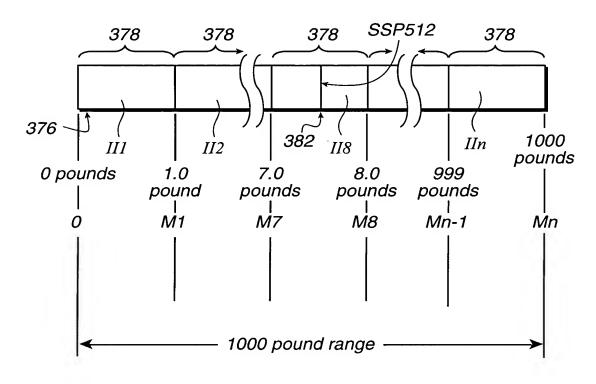
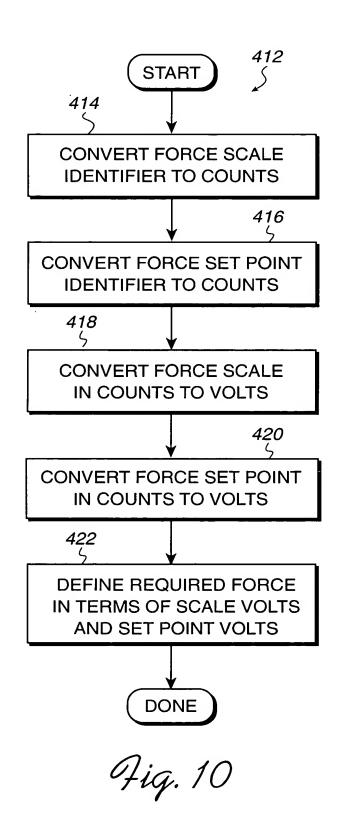
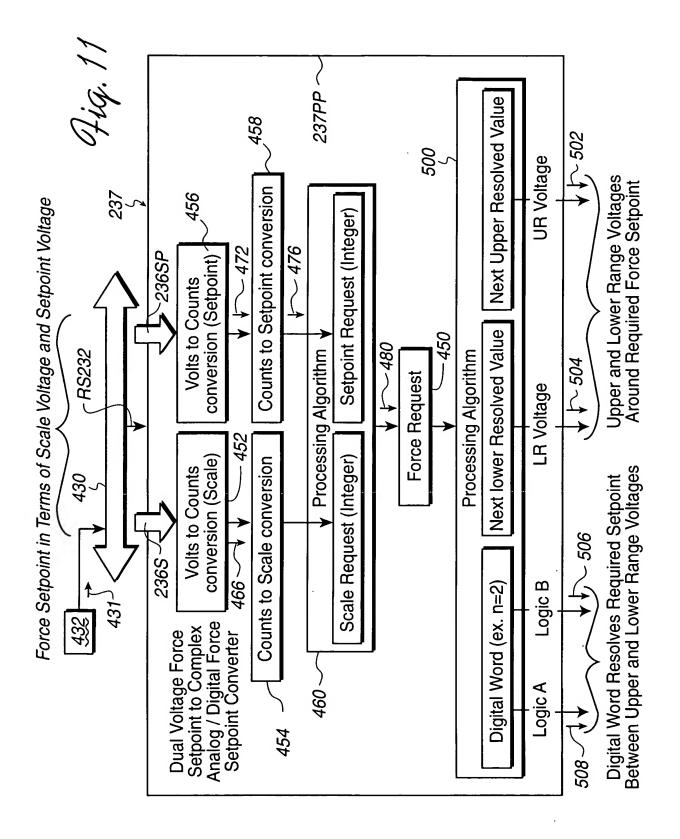


Fig. 9





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